Mooney, Michael Sat 1/10/04 9:00 AM Start: Sat 1/10/04 9:30 AM End: (none) Recurrence: ((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 BRS 199 orfabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and SiO\$6 USPAT; US-PGPUB 2004/01/07 11:14 ((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 BRS 536 orfabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and (SiO\$6 or silicon) **USPAT: US-**2004/01/07 11:15 **PGPUB** (((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 BRS 172 orfabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and (SiO\$6 or silicon)) and (dielectric\$6 with (film or coat\$6)) USPAT; US-PGPUB 2004/01/07 11:40 ((((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 orfabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and (SiO\$6 or silicon)) and (dielectric\$6 with (film or coat\$6))) and (optic\$6 with (ax\$6 or port)) USPAT; US-PGPUB 2004/01/07 11:18 (((((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 **BRS** 35 orfabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and (SiO\$6 or silicon)) and (dielectric\$6 with (film or coat\$6))) and (optic\$6 with (ax\$6 or port))) and cavit\$6 USPAT; US-PGPUB 2004/01/07 11:36 USPAT; US-PGPUB 2004/01/07 11:35 sacrificial with etch-stop 0 BRS 66 ((((((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 BRS 22 orfabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and (SiO\$6 or silicon)) and (dielectric\$6 with (film or coat\$6))) and (optic\$6 with (ax\$6 or port))) and cavit\$6) and (sacrificial with layer\$6) USPAT: US-PGPUB 2004/01/07 11:41 ((((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 BRS orfabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and (SiO\$6 or silicon)) and (dielectric\$6 USPAT; US-PGPUB 2004/01/07 11:53 with (film or coat\$6))) and ((mirror or reflect\$8) with cavit\$6) (coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 orfabricat USPAT; US-PGPUB 2004/01/08 15:11 \$6 or manufactur\$6)) and (etch\$8 with layer\$6) BRS 25 ((((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 orfabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and (SiO\$6 or silicon)) and (dielectric\$6 with (film or coat\$6))) and ((mirror or reflect\$8) with cavit\$6)) and (sacrificial with layer\$6) USPAT: US-**PGPUB** 2004/01/07 11:54 ((((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 BRS orfabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and (SiO\$6 or silicon)) and (dielectric\$6 with (film or coat\$6))) and ((mirror or reflect\$8) with (cavit\$6 or filter or laser)) USPAT; US-PGPUB 2004/01/08 14:42 (((((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 BRS orfabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and (SiO\$6 or silicon)) and (dielectric\$6 with (film or coat\$6))) and ((mirror or reflect\$8) with (cavit\$6 or filter or laser))) and (sacrificial with layer\$6) USPAT; US-PGPUB 2004/01/07 14:22 USPAT; US-PGPUB 2004/01/07 17:59 0 **BRS** "20020168136" 1

1

0

USPAT; US-PGPUB 2004/01/07 18:18

5986796.pn. USPAT; US-PGPUB 2004/01/07 18:14

"20020168136" and (support with port)

BRS

BRS

1

1

	0	100	LIGDAT LIG DODLID	0004/01/05 10 22	
BRS	1	5986796.pn. and (mirror same etch\$6)	USPAT; US-PGPUB	2004/01/07 18:33	
BRS	1	"20020168136" and (etch-stop with optic\$6	USPAT; US-1	PGPUB 2004/01/07 21:23	
BRS	1	"20020168136" and (etch\$6 with coat\$6)	USPAT; US-PGPUB	2004/01/07 21:23	
BRS	0	5986796.pn. and (etch\$6 with coat\$6)	USPAT; US-PGPUB	2004/01/07 21:22	
BRS	0	5986796.pn. and (etch\$6 with coat\$6) and (etch	etch\$6 with \$6stop)	USPAT; US-PGPUB	
BRS	1	"20020168136" and (etch\$6 with coat\$6)	USPAT; US-PGPUB	2004/01/07 21:23	
BRS	1	"20020168136" and (etch-stop with optic\$6	S) USPAT; US-1	PGPUB 2004/01/07 21:47	
BRS	1	("20020168136" and (etch\$6 with coat\$6))	•		
(*200 BRS	2016813 1	66" and (etch\$6 with \$6stop)) USPAT; US-I "20020168136" and (device near1 layer)	USPAT; US-PGPUB		
	0	` ,	•		
BRS	1	"20020168136" and (etch\$6 with \$6stop)	USPAT; US-PGPUB	2004/01/07 21:28	
BRS	1	"20020168136" and (coat\$6 with optic\$6)	USPAT; US-PGPUB	2004/01/07 21:47	
BRS	33	((((coat\$6 with layer\$6) and (MEMS or MC	, , , ,	,	
		r manufactur\$6)) and (etch\$8 with layer\$6))			
with (film or coat\$6))) and ((mirror or reflect\$8) with (cavit\$6 or filter or laser)) and ((dielectric\$6 with (film or coat\$6)) same thick\$6) USPAT; US-PGPUB 2004/01/08 14:48 0					
	,,	-		U	
BRS		(((((coat\$6 with layer\$6) and (MEMS or MC	, , , ,	,	
orfabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and (SiO\$6 or silicon)) and (dielectric\$6 with (film or coat\$6))) and ((mirror or reflect\$8) with (cavit\$6 or filter or laser)) and ((dielectric\$6 with (film or					
		thick\$6)) and metal USPAT; US-PGPUB	2004/01/08 14:49	0	
BRS	26	(((((coat\$6 with layer\$6) and (MEMS or MC			
orfabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and (SiO\$6 or silicon)) and (dielectric\$6					
		coat\$6))) and ((mirror or reflect\$8) with (cavi			
coat\$	6)) same	thick\$6)) and (metal with (coat\$6 or layer\$6)) USPAT; US-I	PGPUB 2004/01/08 14:52	
DDG			201 (C) 1 ((1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1	
BRS		(((((coat\$6 with layer\$6) and (MEMS or MC	, , , ,	,	
orfabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and (SiO\$6 or silicon)) and (dielectric\$6					
		coat\$6))) and ((mirror or reflect\$8) with (cavi			
coat\$		thick\$6)) and (metal with (coat\$6 or layer\$6)1/08 14:53) with (reflect\$6 or min	rror\$3)) USPAT; US-PGPUB	
BRS	5	(coat\$6 with layer\$6) and (MEMS or MOE	MS) and ((process or m	nethod) with (mak\$6 orfabricat	
		ctur\$6)) and (etch\$8 with layer\$6) and (dop\$6	with curv\$7) USPA	T; US-PGPUB 2004/01/08	
15:21 BRS	22	0 (MEMS or Moems) and (dop\$6 with curvate	ure) USPAT; US-I	PGPUB 2004/01/08 15:22	
		0			
BRS 19 ((MEMS or Moems) and (dop\$6 with curvature)) not ((coat\$6 with layer\$6) and (MEMS or					
	,	((process or method) with (mak\$6 orfabricat	**	^ `	
(dop\$	o with c	urv\$7)) USPAT; US-PGPUB 2004/01/08 15	0:22	0	